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SUMMARY OF INVENTION

[0003a] In a first aspect, a cover for a component of a polishing apparatus for polishing substrates is provided, the cover comprising a locking mechanism disposed inside the cover and configured to latch together a main body of the component and the cover,

wherein an external surface of the cover exposed to the outside has no recessed portion, and has no horizontal plane, except on a top portion of the cover.

TECHNICAL PROBLEM

[0004] In the environment of usage of such a polishing apparatus as described above, slurry (including fine liquid particles thereof) scatters or floats to adhere to a cover for a component of the polishing apparatus (in particular, a component located in a low position), for example, a cover for a dresser. Most of slurry adherent to the cover runs off downward. If such liquid particles do not run off but are left to stand in a state of being deposited, however, the particles become dry and give rise to solidified matter. If this solidified matter should drop onto a substrate being polished, serious problems may occur, including the problem of scratches being produced on a surface to be polished.

[0005] Hence, there is a need for a cover to which a

polishing liquid is less likely to stick and solidify. In addition, the cover is preferably configured to require only small amounts of installation man-hour and time.

SOLUTION TO PROBLEM

[0006] The present invention has been accomplished in order to solve at least some of the above-described problems and can be carried out, for example, in the aspects to be described hereinafter.

[0007] According to a first embodiment of the present invention, there is provided a cover for a component of a polishing apparatus for polishing substrates. This cover is provided with a locking mechanism disposed inside the cover